

Kie Y. Ahn et al.

A Dielectric Layer Forming Method and Devices Formed Therewith

Assignee: Micron Technology, Inc.

Docket No. MI22-1534

## INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.

Copies of documents listed on the Form PTO-1449 are enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 18 ort 2002

Attorney:

James F I

Reg. No.: 44,854

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